Magnetic Properties of CoTbNi and FePtCo Ternary Alloy Thin Films Prepared by DC Magnetron Sputtering for Ultra-high Density Storage Media

Thesis submitted

By **Rajib Kumar Basumatary** Roll No. PHY PHD 02 Regn. No. 057119 of 2017-18

In Partial Fulfilment of the Requirements for the Award of the Degree of

Doctor of Philosophy in Physics



Faculty of Science & Technology Department of Physics BODOLAND UNIVERSITY

Kokrajhar-783370

Assam, India

June 2023

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Under the Guidance of

Dr. Rajeeb Brahma (Supervisor) Assistant Professor Department of Physics Bodoland University Dr. Sandeep Kumar Srivastava (Co-Supervisor) Associate Professor Department of Physics Central Institute of Technology Kokrajhar

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DEDICATION

I dedicate this thesis to my loving parents and rest of my family who taught me that it is never too late to change careers to achieve goals.

I also like to dedicate this thesis to my Ph.D. supervisors without whose support and encouragement the research works carried out in this thesis would have been impossible.

Lastly, I also dedicate this thesis to almighty god for giving me strength and patience to face all the challenges.

DECLARATION

I hereby declare that this thesis titled "Magnetic Properties of CoTbNi and FePtCo Ternary Alloy Thin Films Prepared by DC Magnetron Sputtering for Ultra-high Density Storage Media" is the result of my own research work which has been carried out under the guidance of Dr. Rajeeb Brahma of Bodoland University and Dr. Sandeep Kumar Srivastava of Central Institute of Technology Kokrajhar.

I further declare that this thesis as a whole or any part thereof has not been submitted to any university or institute for award of any degree or diploma.

This thesis contains less than 300 (Three hundred) pages excluding bibliography and captions.

Date: 15/06/2023 Place: JKoKrayhar

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Date: 15/06/2023

CERTIFICATE

This is to certify that the work described in the dissertation report entitled "Magnetic Properties of CoTbNi and FePtCo Ternary Alloy Thin Films Prepared by DC Magnetron Sputtering for Ultra-high Density Storage Media" submitted by Mr. Rajib Kumar Basumatary", a Ph. D. student in the Department of Physics, Bodoland University, Kokrajhar, Assam (India) for the award of the degree of Doctor of Philosophy has been carried out under my guidance and supervision. Mr. Rajib Kumar Basumatary has fulfilled all the requirements under Ph.D. rules and regulations of Bodoland University for submitting his thesis for the award of Ph.D. degree. The thesis is the result of his own-investigation and to the best of my knowledge, this dissertation carried out by the candidate has not been submitted to any other University or Institute for any degree or diploma.

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Date: 15/06/23 Place: Koknayhar



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Certificate by Co-Supervisor

This is to certify that the work described in the thesis titled "Magnetic Properties of CoTbNi and FePtCo Ternary Alloy Thin Films Prepared by DC Magnetron Sputtering for Ultra-high Density Storage Media" submitted by Mr. Rajib Kumar Basumatary, a Ph. D. student in the Department of Physics, Bodoland University, Kokrajhar, Assam (India) for the award of the degree of Doctor of Philosophy has been carried out under my guidance and supervision. Mr. Rajib Kumar Basumatary has fulfilled all the requirements under Ph.D. rules and regulations of Bodoland University for submitting his thesis for the award of Ph.D. degree. The thesis is the result of his own-investigation and to the best of my knowledge, this thesis carried out by him has not been submitted to any other University or Institute for any degree or diploma.

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